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5 An article (e.g. a semiconductor wafer) is held in an article holder by means of a
number of gas flows emitted from gas vortex chambers. Some of the gas flows act to
cool an adjacent article portion more than the other gas flows. For example, some of the
vortex chambers emit more gas per unit of time than the other chambers. More cooling is
provided to those portions of the article which are heated more during processing.
10 Greater temperature uniformity can be achieved.